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[10] Technology dependance of reflective optical systems for EUV and astronomical applications

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Manufacturing and optical design technologies have placed considerable limitations on the realization of highly useful reflective optical systems. However, recent advances in manufacturing technology combined with novel optical designs that take advantage of the total technology potential has greatly increased the capability of reflective optical systems. This has led to the creation of new reflective optical systems for various applications which afford compactness, lightweight, rigidity and athermal features as well as low cost. Several examples of such systems which cover single and multiple wavebands spanning soft X-ray and near EUV wavelengths to visible and far infrared wavelengths will be described.

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